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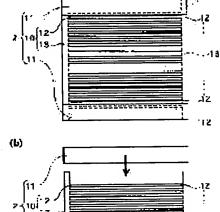
TSURUOKA YOSHIHISA

(54) ORGANIC EL ELEMENT, MASK FOR MANUFACTURING THE ELEMENT AND MANUFACTURE OF THE ELEMENT

(57)Abstract:

PROBLEM TO BE SOLVED: To miniaturize jigs of an upper electrode forming mask, in an organic EL element of an X-Y matrix.

SOLUTION: An X-Y matrix driving organic EL element wherein a first electrode, an organic layer and a second electrode are laminated on a substrate has a dummy electrode parallel to the second electrode. A mask 2 for deposition of the second electrode and the dummy electrode has an electrode mask part 10 coupling a plurality of zonal masking parts 12 by a pair of coupling parts 13, and two terminal mask parts 11 covering an upper end and a lower end of the electrode mask part 10. The electrode mask part 10 is set on the organic layer to add the prescribed tensile force to the masking parts 12. The terminal mask parts 11 are set on the electrode mask part 10 so as to cover at least a part of the respective masking parts 12 at both ends. Then, a second electrode forming material is deposited on the substrate side through the electrode mask part 10 and



11 12

the terminal mask parts 11, to form the second electrode and the dummy electrode. Thereby, tension added to the mask 2 can be lowered, thus jigs used in the deposition device can be miniaturized and weight-saved.

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